

Sustained production of H₂O₂ on irradiated TiO₂ – fluoride systems

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UV irradiation of fluorinated TiO₂ suspensions in water, in the presence of oxygen and a hole scavenger, leads to the production of H₂O₂ with steady state concentration levels up to 1.3 millimolar; the H₂O₂ formation rate follows the TiO₂ surface speciation, being maximum when the surface is completely covered by ≡Ti–F groups; these results outline the importance of surface speciation on the photocatalytic process.

In recent years photocatalytic reactions over semiconductor oxides have been investigated in depth.^{1,2} The formation of reactive oxygen species, namely OH[•], O₂^{•-}, H₂O₂, during catalytic processes on metal oxide semiconductors is of paramount importance for practical application of both photocatalysis (e.g. water and air detoxification, self cleaning and self disinfecting surfaces) and metal oxide catalysed oxidation of organic compounds.^{3,4} Formation of H₂O₂^{5–9} and superoxide^{5,9,10} from irradiated TiO₂ particles has been reported. Concentration levels of H₂O₂ noticed so far are in the micromolar range. Although now there is a consensus on the reductive mechanism involving O₂ reaction with a conduction band electron (e_{CB}),^{7,8} the detailed pathway of H₂O₂ production and the influence of parameters like pH, the presence of anions, the nature and concentration of hole scavenger, are still missing. Recently the strong influence of surface adsorbed ions on the photocatalytic oxidation mechanism of organic substrates over TiO₂ was demonstrated.^{11–13} Surface complexation by the redox inactive fluoride ion leads to an increase in the degradation rate of organic substrates that react mainly through an OH[•] radical mediated pathway, with a bell shaped dependence on pH, reflecting the distribution of ≡Ti–F;¹¹ a kinetic analysis of competition experiments with different OH[•] scavengers allowed the quantification of the relative role of direct electron transfer and mediated oxidation through OH[•] radical (free or adsorbed) in the photocatalytic degradation of phenol, showing that over TiO₂/F the transformation proceeds almost entirely through mediated oxidation by free OH[•], whereas on naked TiO₂ about 10% is due to a direct hole oxidation and the 90% to OH[•] (adsorbed).¹² In this note we present the results of the surface fluorination of TiO₂ on the reductive processes started by e_{CB}, specifically the production of H₂O₂ through oxygen reduction.

The irradiation experiments were carried out on 5 ml of aqueous suspension containing the hole scavenger (formic acid or phenol) and 0.5 g L⁻¹ of catalyst (TiO₂ P25 powder, Degussa), using a 40 W fluorescent lamp (TL K 40W 05 Philips, max. emission at 360 nm). Fluorides were added as HF. The pH before irradiation was adjusted by adding HNO₃ or NaOH solutions. Total photonic flux was 1.0 × 10⁻⁵ Ein min⁻¹. The filtered suspensions were analysed by the appropriate analytical technique (HPLC, ion

chromatography or spectrophotometry). A careful cleaning of TiO₂ powder to eliminate organic and ionic impurities was carried out by irradiating in air a TiO₂ suspension for two days, then washing the powder until no chloride ions were detected. The H₂O₂ was quantified by the peroxidase-catalysed oxidation of either *p*-phenylenediamine^{14a} or phenol/4-aminoantipyrine^{14b} (when phenol is employed as hole scavenger).

The first striking feature of photocatalytic processes over TiO₂/F in the presence of a hole scavenger is the production of H₂O₂ with steady state concentration levels in the millimolar range (Fig. 1).

These concentrations are at least 100 times higher than those reported so far. The maximum photonic efficiency attained for H₂O₂ photoproduction is 1.25% (pH 3.2, [HF] + [F⁻] = 10 mM). Without fluoride, the H₂O₂ in the photocatalytic system is not detectable (below 0.1 μM). A possible role in the enhancement of oxygen adsorption over TiO₂/F could be relevant.¹⁵ The second feature is the bell shaped pH dependence of the initial rate of H₂O₂ production (Fig. 2). The maximum rate is obtained around pH 3.1 and the curve is very similar to the dependence on the pH of ≡Ti–F coverage.¹¹ Similar results were obtained by using phenol as hole scavenger. However, the ratio between the initial rates of H₂O₂ production and phenol degradation is half of that observed with formic acid (0.16 vs. 0.31 at pH 3.2). This result can be explained by the reducing ability of the radical generated by the one electron oxidation of HCOOH, which could give the current doubling effect in photoelectrochemical systems, or, as in the present case, produce an additional molecule of O₂^{•-} from the reduction of O₂.¹⁶

No H₂O₂ is formed in the absence of: 1) fluoride ions; 2) a hole scavenger; 3) oxygen, even in the presence of fluoride and Ag⁺ as

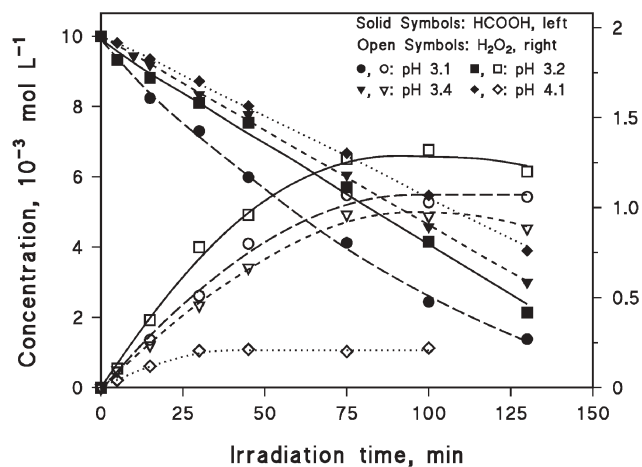


Fig. 1 H₂O₂ production in the photocatalytic degradation of formic acid over fluorinated TiO₂. Conditions: TiO₂ 0.5 g L⁻¹, HCOOH 1.0 × 10⁻² M, [HF] + [F⁻] = 1.0 × 10⁻² M. Air saturated suspension.

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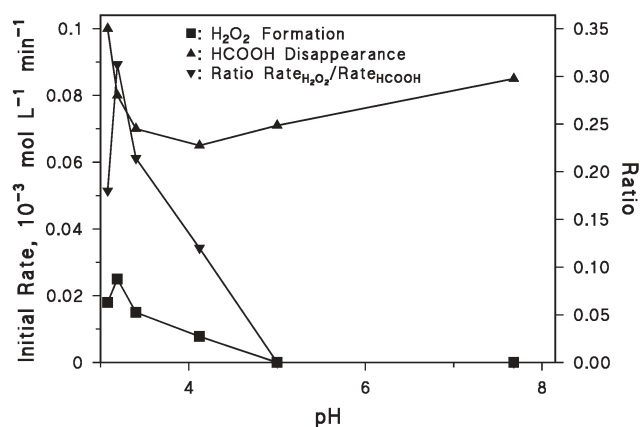


Fig. 2 Influence of pH on the initial rate of the photocatalytic H₂O₂ production. Data are obtained from experiments like those reported in Fig. 1.

electron scavenger. On the other hand, the loss of H₂O₂ under photocatalytic conditions is inhibited by the presence of fluoride. Fig. 3 reports the disappearance curves of H₂O₂ at pH 4. The ratio of the initial rate of H₂O₂ disappearance in the absence and in the presence of fluoride ions (1 × 10⁻² M) is R^{deg}_{H₂O₂} = 19.

The ability of peroxides to complex Ti(IV) compounds¹⁷ and the surface of titanium dioxide has long been known.¹⁸ However, no equilibrium adsorption data are reported. Recently it was noticed that there was a pH dependence of the formation of ≡Ti-OOH species.¹⁹ The insert of Fig. 3 reports the adsorption isotherms of H₂O₂ at pH 4 over TiO₂ P25 in the absence and in the presence of fluoride ions (1 × 10⁻² M). The competition of fluoride with H₂O₂ for the TiO₂ surface sites is evident. Interestingly, the ratio of the H₂O₂ adsorbed in the absence and in the presence of fluoride, when [H₂O₂]_{free} = 1 × 10⁻³ M, is R^{ads}_{H₂O₂} ≈ 22 (Fig. 3, insert). Thus, a possible role of the redox inert ligand is the inhibition of the formation of surface superoxo/peroxo species. When these are

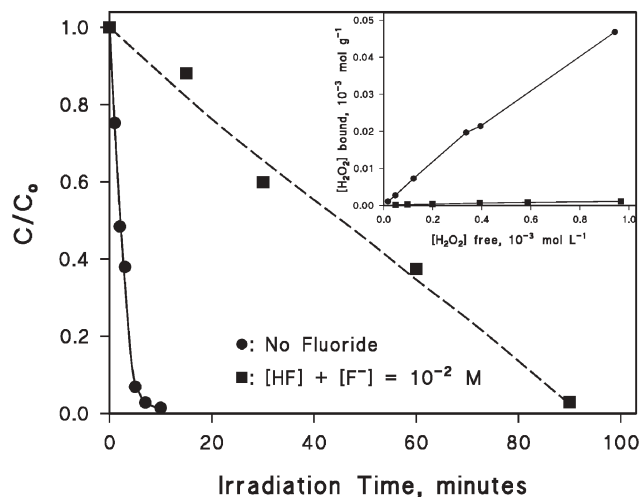
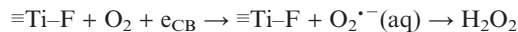
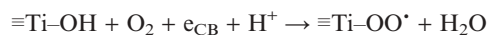


Fig. 3 Photocatalytic degradation of H₂O₂ (C₀ = 1 × 10⁻³ M) in the presence and in the absence of fluoride. Conditions: TiO₂ 0.5 g L⁻¹, pH 4.0. Air saturated suspension. Insert: H₂O₂ Adsorption isotherm on TiO₂ at pH 4 in the presence and the absence of fluoride. Conditions: TiO₂ 5 g L⁻¹, pH 4.0.

produced from O₂ reduction by e_{CB}, in the presence of F⁻ a release in solution of HO₂[•]/H₂O₂ is achieved:



The ratio between R^{deg}_{H₂O₂} and R^{ads}_{H₂O₂} is 19/22 ≈ 0.86, suggesting that the photocatalytic transformation of H₂O₂ involves almost entirely the reaction of the surface ≡Ti-OOH complexes and not free H₂O₂. Anions without surface complexing abilities (e.g. nitrate) do not lead to H₂O₂ formation. These results are consistent with the reported production of H₂O₂ over irradiated ZnO,⁷ the surface of which is not complexed by H₂O₂.

In conclusion, the modification of the TiO₂ surface through anion complexation has a strong influence on the reductive pathways started by photogenerated e_{CB}. The major effect of the presence of oxygen as electron scavenger is the sustained production of hydrogen peroxide, with steady state concentration levels of 1–1.3 mM, nearly 100 times the levels reported so far. Experimental results are explained in terms of a competition of the fluoride with superoxide/peroxide species for the surface sites of TiO₂, thus inhibiting H₂O₂ degradation.†

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Notes and references

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- 1 C. Minero, V. Maurino and E. Pelizzetti, in *Semiconductor Photochemistry and Photophysics* (Molecular and Supramolecular Photochemistry, Vol. 10), V. Ramamurthy, K. S. Schanze (Eds.), Marcel Dekker, New York, 2003, pp. 211–229.
- 2 A. Fujishima, T. N. Rao and D. A. Tryk, *J. Photochem. Photobiol., C: Photochem. Rev.*, 2000, **1**, 1.
- 3 D. M. Murphy, E. W. Griffiths, C. C. Rowlands, F. E. Hancock and E. Giamello, *Chem. Commun.*, 1997, 2177.
- 4 D. Tantanak, M. A. Vincent and I. H. Hillier, *Chem. Commun.*, 1998, 1031.
- 5 R. Cai, K. Hashimoto, A. Fujishima and Y. Kubota, *J. Electroanal. Chem.*, 1992, **326**, 345.
- 6 J. R. Harbour, J. Tromp and M. L. Hair, *Can. J. Chem.*, 1985, **63**, 204.
- 7 C. Kormann, D. W. Bahnemann and M. R. Hoffmann, *Environ. Sci. Technol.*, 1988, **22**, 798.
- 8 R. Cai, Y. Kubota and A. Fujishima, *J. Catal.*, 2003, **219**, 214.
- 9 H. Goto, Y. Hanada, T. Ohno and M. Matsumura, *J. Catal.*, 2004, **225**, 223.
- 10 L. Cermenati, P. Pichat, C. Guillard and A. Albin, *J. Phys. Chem. B*, 1997, **101**, 2650.
- 11 C. Minero, G. Mariella, V. Maurino and E. Pelizzetti, *Langmuir*, 2000, **16**, 2632.
- 12 C. Minero, G. Mariella, V. Maurino, D. Vione and E. Pelizzetti, *Langmuir*, 2000, **16**, 8964.
- 13 H. Park and W. Choi, *J. Phys. Chem. B*, 2004, **108**, 4086.
- 14 (a) H. Bader, V. Sturzenegger and J. Hoigné, *Water Res.*, 1988, **9**, 1109; (b) J. E. Frew, P. Jones and G. Scholes, *Anal. Chim. Acta*, 1983, **155**, 139.

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- 15 G. Munuera, A. Gonzales-Elipse, V. Rives-Arnau, J. A. Navio, P. Malet, J. Soria, J. C. Conesa and J. Sanz, in *Studies in Surface Science and Catalysis*, M. Che, G. C. Bond (Eds.), Elsevier, Amsterdam, The Netherlands, 1985; Vol. 21, pp. 113–125.
- 16 (a) N. Hykaway, W. M. Sears, H. Morisaki and S. R. Morrison, *J. Phys. Chem.*, 1986, **90**, 6663; (b) S. R. Morrison, *Electrochemistry at Semiconductor and Oxidized Metal Electrodes*, Plenum Press, New York, 1980, p. 257.
- 17 J. Muhlebach, K. Muller and G. Schwarzenbach, *Inorg. Chem.*, 1970, **9**, 2381.
- 18 A. H. Boonstra and C. A. H. A. Mutsaers, *J. Phys. Chem.*, 1975, **79**, 1940.
- 19 X. Li, C. Chen and J. Zhao, *Langmuir*, 2001, **17**, 4118.